

FORM PTO-1449 INFORMATION DISCLOSURE STATEMENT				Atty Docket		Application No.	
				TAI 145		To Be Assigned	
				Applicant			
				Toyokazu Sakata			
Filing Date				Group Unit			
November 26, 2003				To Be Assigned			
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-Class	Filing Date
LV	AA	6,355,572	03/12/02	Ikegami			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Sub-Class	Translation
LV	AK	7-94483	04/07/95	Japan			Abstract
LV	AL	2001-77086	03/23/01	Japan			Abstract
	AM						
	AN						
OTHER (Including Author, Title, Date, Pertinent Pages, etc.)							
LV	AO	"Dry Etching of Organic Low Dielectric Constant Film without Etch Stop Layer" M.Mizumura et al. JJAP, Vol. 41, pp. 425-427					
LV	AP	"Highly Selective Etching of Organic SOG to SiN for Cu Damascene Interconnects Using New Gas Chemistry of C ₄ F ₈ /N ₂ /Ar" S. Uno et al. Proc. Of Dry Process Symp., pp. 215-220(1999)					
	AQ						
Examiner LAN VINU				Date Considered 7/18/05			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							